

Figure 1. Schematic illustration of a MOSFET structure patterned with SCALES process and AS-ALD.

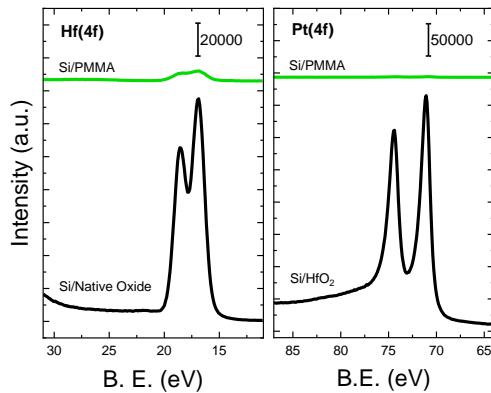


Figure 2. XPS spectra of Hf(4f) and Pt(4f) regions showing selectivity of the HfO₂ and Pt depositions.

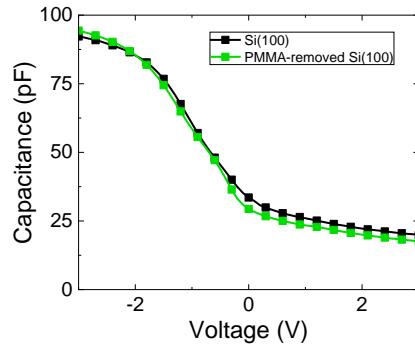


Figure 3. C-V curves for Si/HfO₂/evaporated Al gate stack.